Ref #	Hits	Search Query	DBs	Default Operator	Plurals	Time Stamp
L1	457	(substrate wafer mask) near6 monomer and (detect\$3 measur\$3 inspect\$3) with particles	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/10/07 12:22
L2	43	1 and laser and scanner	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/10/07 12:18
L3	388	(substrate wafer mask) near6 monomer and (detect\$3 measur\$3 inspect\$3) near9 particles	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/10/07 12:23
L4	8	(wafer mask) near6 monomer and (detect\$3 measur\$3 inspect\$3) near9 particles	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/10/07 12:27
L5	0	((chemical near compound) with polymeriz\$5) near9 (substrate wafer) and (detect\$3 measur\$3 inspect\$3) near9 particles	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/10/07 12:32
L6	43	((compound) with polymeriz\$5) near9 (substrate wafer) and (detect\$3 measur\$3 inspect\$3) near9 particles	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/10/07 12:29
L7	22	((compound) with polymerization) near9 (substrate wafer) and (detect\$3 measur\$3 inspect\$3) near9 particles	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/10/07 12:31
L8	61514	chemical near compound	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/10/07 12:31
L9	722	((chemical near compound) with polymeriz\$5)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/10/07 12:32

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L10	1	9 and particles near9 wafer	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/10/07 12:33
L11	367	9 and particles	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/10/07 12:33
L12	21	9 and particles near9 substrate	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/10/07 12:36
L13	110	monomer and laser near15 (particle near9 substrate)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/10/07 12:49
L14	11	13 and scanner	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/10/07 12:37
L15	18	13 and counter	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/10/07 12:37
L16	222	monomer and laser near2 scanner and particle with substrate	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/10/07 12:54
L17	102	16 and counter	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/10/07 12:49
L18	89	17 and polymeriz\$5	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/10/07 12:50
L19	25	18 and metal and copper and vapor near phase	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/10/07 12:50

L20	1295	monomer and laser near2 scanner	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/10/07 12:58
L21	647	monomer near6 polymeriz\$5 and laser near2 scanner	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/10/07 12:54
L22	126	21 and particle with substrate	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/10/07 12:55
L23	651	monomer and particle near2 counter	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/10/07 12:58
L24	<del>4</del> 6	23 and polymeriz\$5 and laser and scanner	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/10/07 13:01
L25	2	"20020163831"	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/10/07 13:00
L26	255	23 and polymeriz\$5 and laser	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/10/07 13:03
L27	145	26 and (wafer semiconductor integrat\$5)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/10/07 13:03
L28	117	26 and (wafer semiconductor (integrat\$5 near device))	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/10/07 13:08
L29	2	10/666586	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/10/07 13:08

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L30	191	Gilton near Terry near L	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/10/07 13:12
L31	2	30 and monomer	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/10/07 13:12
L32	20149	substrate with monomer	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/10/07 13:12
L33	842	32 and (detect\$3 or measur\$3) near9 particle	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/10/07 13:13
L34	758	33 and polymeri\$5	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/10/07 13:13
L35	59	34 and laser and scanner	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/10/07 13:14
L36	15	Micron near Technology and substrate with monomer	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/10/07 13:15

Ref #	Hits	Search Query	DBs	Default Operator	Plurals	Time Stamp
L1	. 4	"6646243" and cataly\$3 and particle	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/10/07 13:59
L2	4	"6646243" and cataly\$3 and particle and monomer	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/10/07 14:22
L3	1	"6646243" and detect\$3 with particle	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/10/07 14:23
L4	6	"6646243" and detect\$3 and particle	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/10/07 14:23
L5	6	"6646243" and detect\$3 and particle\$3	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/10/07 15:20
L6	4	"6646243" and size near3 particle\$3	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/10/07 15:21
L7	0	"6646243" and number near3 particle\$3	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/10/07 15:21
L8	0	"6646243" and location\$3 near3 particle\$3	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/10/07 15:21
L9	3858	particle near counter	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/10/07 15:21

L10	3	(particle near counter) with ((number and positions and size) near4 particle)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/10/07 15:23
L11	1285	(particle near counter) with ((number positions size) near4 particle)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/10/07 15:24
L12	12	11 and laser near2 scanner	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/10/07 15:24
L13	1572	(particle near counter) with ((number positions size))	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/10/07 15:24
L14	12	13 and laser near2 scanner	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/10/07 15:24
L15	4	(particle near counter) with (laser near3 scanner)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/10/07 15:26
L16	3858	(particle near counter) with particles	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/10/07 15:30
L17	2428	16 and size and number	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/10/07 15:26
L18	110	17 and scanner	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/10/07 15:26
L19	77	18 and laser	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/10/07 15:27

L20	16	19 and fluorescen\$3	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/10/07 15:27
L21	694	(particle near counter) with size near3 particle\$3	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/10/07 15:30
L22	391	21 and number near3 particle\$3	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/10/07 15:30
L23	6	22 and laser and scanner	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/10/07 15:31
L24	207	22 and laser	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/10/07 15:32
L25	104	24 and (wafer semiconductor)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/10/07 15:33
L26	53	25 and (detect\$3 near9 particle\$3)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/10/07 15:33
L27	46	24 and (wafer)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/10/07 15:33
L28	23	27 and (detect\$3 near9 particle\$3)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/10/07 15:34